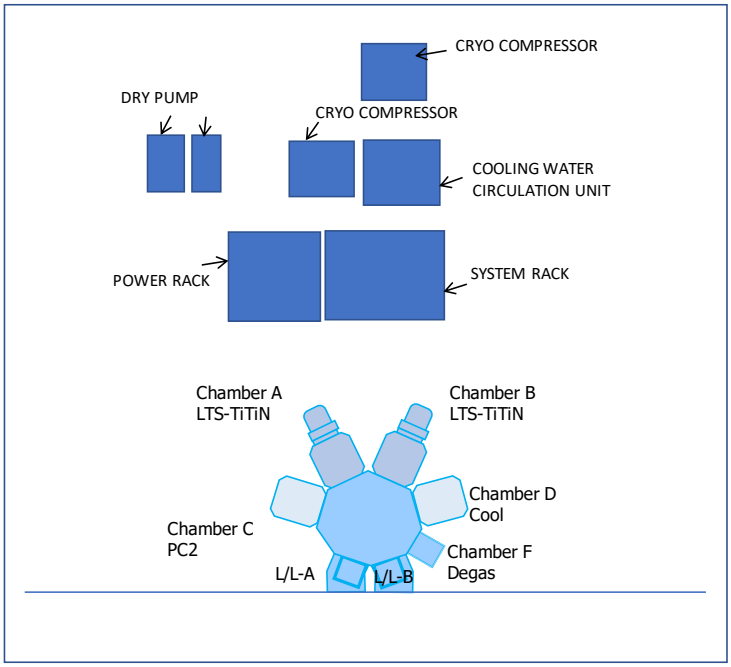
LTS-Ti/TiN sputtering system

Centura PVD made by AMAT

Serial number	2581	
Chamber configuration		
Chamber A	LTS-Ti	(ESC)
Chamber B	LTS-Ti	(ESC)
Chamber C	PreClean2	
Chamber D	Cooling	
Chamber E	none	
Chamber F	Degas/Orienter	
cryopump	CTI-ONBOARD x 3 units	
cryo compressor	CTI-CRYOGENICS 9600×2	
NESLAB	One	
system rack	×1	
generator rack	×1	
dry pump	Ebara S50P x 1 unit	
	Ebara S20P x 1 unit	
RF power supply for PC2	RFPP _LF-10 x 1 unit	
	COMODEL_13.56MHZ_CPS1001S	
DC power supply	AE company_MDX-L12×4 units	
Clean room side_CRT rack		



Note: Missing Cryo Pumps for PVD and Buffer Chambers